

Figure S1.  $S$ ,  $D^*$ ,  $R$  of  $\text{TiO}_2$  NRAs/ $\text{SiO}_2$ / $\text{Si}$  and  $\text{H}:\text{TiO}_2$  NRAs/ $\text{SiO}_2$ / $\text{Si}$  under 950 nm light at -7 V

	$R$ (A/W)	$S$ ( $\times 10^4 \text{cm}^2 \text{W}^{-1}$ )	$D^*$ ( $\times 10^{11} \text{cmHz}^{1/2} \text{W}^{-1}$ )
Fabricated	6.92	3.42	8.5
350°C	11.4	87	55.6
500°C	7.52	2.75	4.4

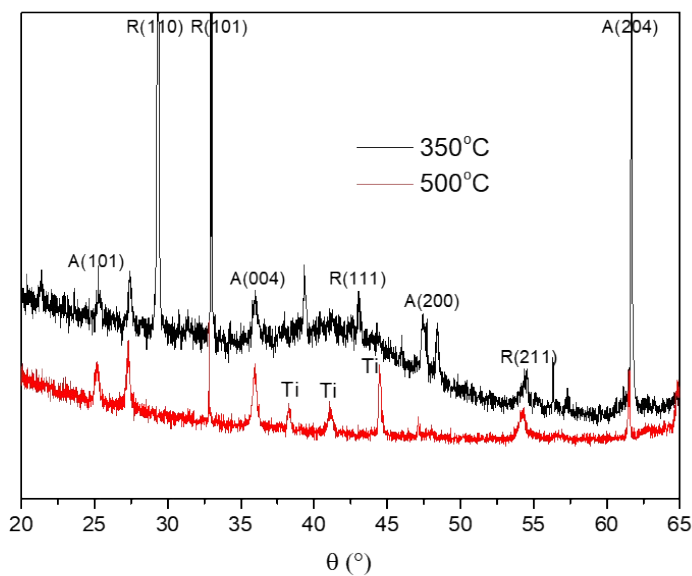


Figure S2. XRD spectra of  $\text{H}:\text{TiO}_2$  nanorods annealed in hydrogen at various temperatures (350 and 500 °C).

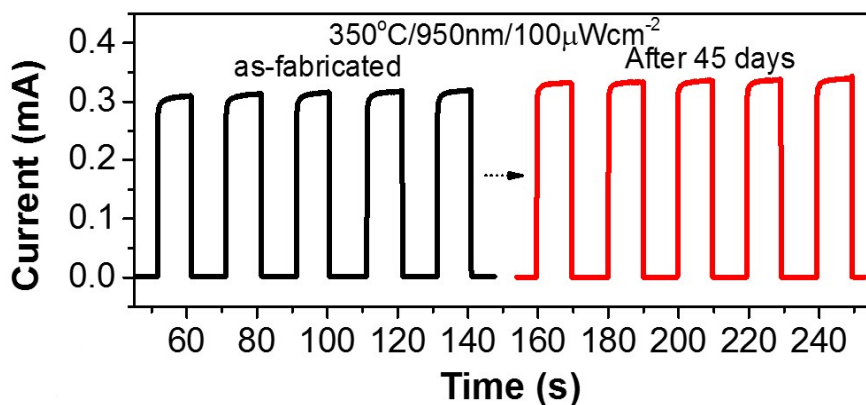


Figure S3. Stability and reproducibility of fabricated  $\text{H}:\text{TiO}_2$  NRAs/ $\text{SiO}_2$ / $\text{Si}$  after storing in ambient condition for 45 days.

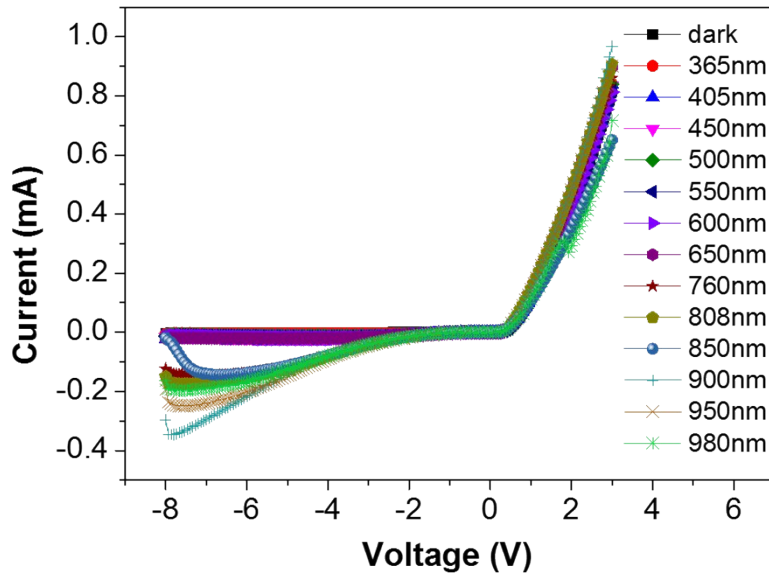


Figure S4.  $I$ - $V$  curves of the H:TiO<sub>2</sub> NRAs/SiO<sub>2</sub>/Si heterojunction photodetector ranging from the UV to NIR light at 100  $\mu\text{Wcm}^{-2}$ .

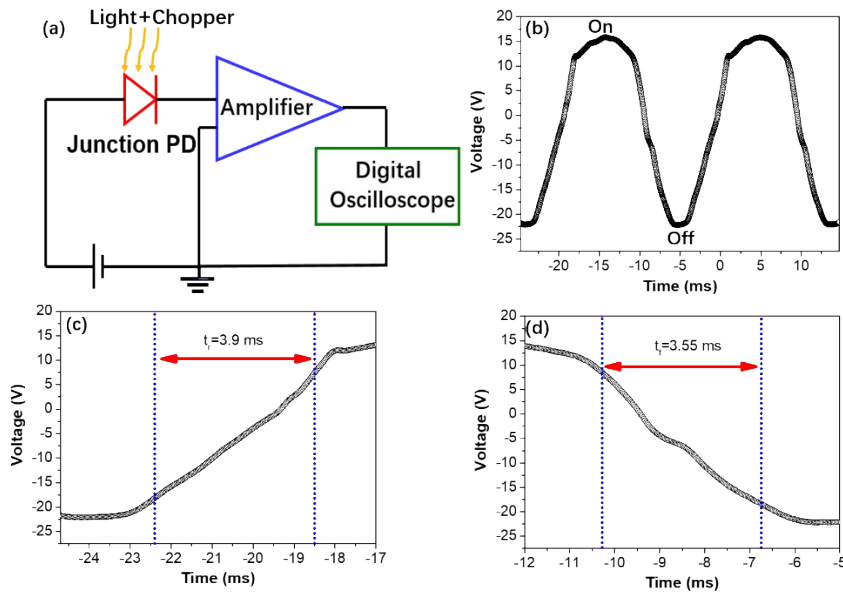


Figure S5. (a) Schematic diagram of measurement circuit of transient response of H:TiO<sub>2</sub> NRAs/SiO<sub>2</sub>/Si photodetector. (b) Transient response of the H:TiO<sub>2</sub> NRAs/SiO<sub>2</sub>/Si photodetector measured under the frequency of 50 Hz under 900 nm light. (c and d) Characteristic response times at (c) rise edge and (d) fall edge.

As shown in Fig. S5, in order to investigate the response and recovery times of H:TiO<sub>2</sub> NRAs/SiO<sub>2</sub>/Si heterojunctions accurately, the schematic diagram of measurement circuit of transient response of H:TiO<sub>2</sub> NRAs/SiO<sub>2</sub>/Si photodetector is

show in Fig. S5a. The amplifier is used to converted the current signal into a voltage signal. The digital oscilloscope is used to collect the voltage signal of the amplifier and output the voltage dependent time curves. As shown in Fig. 5b, the voltage value is related to the operating voltage of the amplifier. Finally, under closer examination, the response and recovery times of the present detector are 3.9 ms and about 3.55 ms respectively, as shown in Fig. 5 c and d.

## **The effect of an insulating SiO<sub>2</sub> layer on the photoresponse of heterojunction**

An insulating SiO<sub>2</sub> layer between the SnO<sub>2</sub> and Si plays an important role in the photoresponse.<sup>1,2</sup> At present, it has been reported that adding the SiO<sub>2</sub> passivation layers can reduce the leakage current and make ZnO/*p*-Si heterojunction exhibit the enhanced on-off ratio.<sup>3</sup> It has been also demonstrated that the carrier multiplication process in the insulating oxide layer can improve the response of PDs. Moreover, it has been mentioned that in this work the thickness of natural SiO<sub>2</sub> layer on Si surface is only about 1.2 nm<sup>4</sup>, which is accord with the optimized SiO<sub>2</sub> thickness (several nanometers) according to reported results.<sup>5</sup> The electric field in the SiO<sub>2</sub> layer is estimated to be  $8.3 \times 10^6$  V/cm at 1 V bias using  $E=V/d$ , where  $E$  is the electric field,  $V$  is the bias voltage, and  $d$  is the thickness of the SiO<sub>2</sub> layers. Under the high intensity of the electric field the photo-generated carriers can tunnel through the SiO<sub>2</sub> layer. Meanwhile, it also is demonstrated that the thicker the SiO<sub>2</sub> layer is, the bigger the bias voltage is.<sup>3</sup> Therefore, the SiO<sub>2</sub> layer plays an important role in the photo-response and the operating bias voltage of SnO<sub>2</sub> nanoparticles thin film/SiO<sub>2</sub>/*p*-Si heterojunction. The optimized SiO<sub>2</sub> thickness is several nanometers according to reported results.<sup>5</sup> If the SiO<sub>2</sub> layer is too thick, it can decrease the effectiveness of the carrier tunneling due to the scattering and trapping of the carriers in the SiO<sub>2</sub> layer, at the same time offers a high potential barrier preventing the carriers from the diffusion and shift tunneling the junction interface.<sup>6</sup> Thus, the photo-response of SnO<sub>2</sub>/SiO<sub>2</sub>/*p*-Si heterojunction would be degraded. At this moment, only a higher light power intensity and a greater bias voltage can remedy the negative impact produced by thicker SiO<sub>2</sub> layer. For example, in ZnO nanorods arrays/SiO<sub>2</sub>/*p*-Si (lateral structure) the SiO<sub>2</sub> layer with about 50 nm make the operating bias voltage of detector be  $\sim 15$  V.<sup>3</sup>

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